

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

JURGEN MUSOLF et al.

Serial No.: Not Yet Assigned

Filed: Herewith

For: ELECTROSTATIC ACTUATORS WITH
INTRINSIC STRESS GRADIENT

Group Art Unit: 3734

Examiner: Not yet assigned

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. §1.56 and in accordance with 37 C.F.R. §§1.97–1.98, information relating to the above–identified application is hereby disclosed. The accompanying Form PTO SB/08A provides a listing of documents that may be relevant to the subject application.

It is requested that the Examiner fully consider the art cited in the accompanying Form SB/08A, initial the left–most column of the form adjacent each cited reference, and return a copy for Applicants' records. It is further requested that the art be cited on the cover of any patent issuing from the subject application.

In accordance with §1.97(b), this Information Disclosure Statement is being filed before the mailing of a first Office Action on the merits of the above–identified application,

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(37 C.F.R. §1.10)

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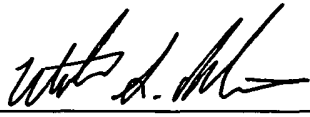
In accordance with §1.98(d), copies of the references are not enclosed herewith because they were previously cited by or submitted to the Patent and Trademark Office in prior Application Serial No. 09/944,867 and a claim for priority under 35 U.S.C. §120 has been made in the instant application. Applicants will provide duplicate copies in the present application only if the Examiner so desires.

This statement should not be construed as a representation that more material information does not exist or that an exhaustive search of the relevant art has been made. Nor does this statement constitute an admission by Applicants or Applicants' agent that the information provided herein is necessarily prior art to Applicants' invention. Moreover, Applicants reserve the right to establish the patentability of the claimed invention over any of the listed documents should they be applied there-against as references. Please charge any deficiency or credit any overpayment to Deposit Account No. 50-0639.

Respectfully submitted,

O'MELVENY & MYERS LLP

Dated: 9/22/03

By: 
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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Complete if Known	
Sheet		1		of 1	
Application Number		Not Yet Assigned			
Filing Date		Herewith			
First Named Inventor		Jurgen Musolf et al			
Group Art Unit		2831			
Examiner Name		Nguyen			
Attorney Docket Number		844004-302			

Examiner Initials *	Cite No. ¹	Document Number Number - Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		US-5,476,836	12-19-1995	Eddy
		US-5,508,255	04-16-1996	Eddy
		US-5,843,870	12-01-1998	Wu et al.
		US-5,883,050	03-16-1999	Yun et al.

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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Examiner Signature	Date Considered
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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